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PATENT
ATTORNEY DOCKET NO.: 053848-5018

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshijiro USHIO et al.

Application No.: 10/774,623

Filed: February 10, 2004

For: METHOD AND DEVICE FOR
SIMULATION, METHOD AND
DEVICE FOR POLISHING, METHOD
AND DEVICE FOR PREPARING
CONTROL PARAMETER OR
CONTROL PROGRAM, POLISHING
SYSTEM, RECORDING MEDIUM,
AND METHOD OF MANUFACTURING
SEMICONDUCTOR DEVICE

Confirmation No.: 1365

Group Art Unit: 3723

Examiner: Jacob K. Ackun

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop AF
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

AMENDMENT UNDER 37 C.F.R. § 1.116

In response to the Final Office Action dated March 27, 2006, the period for response to which extends through June 27, 2006, and pursuant to 37 C.F.R. § 1.116, entry of the following amendment is respectfully requested to place the application in clear condition for allowance or, alternatively, in better form for appeal.